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CUSTOMER NO.: 27623 FORM PTO-1449 Docket Number (Optional) 2133.063USU Applicant INFORMATION DISCLOSURE CITATION IN AN APPLICATION Leib and Mund Filing Date **Group Art Unit** 2811 (Use several sheets if necessary) Herewith 13 April 2005 Not Yet Assigned **U. S. PATENT DOCUMENTS EXAMINER FILING DATE IF** INITIAL DOCUMENT DATE NAME CLASS SUBCLASS **APPROPRIATE** NUMBER A.O.A. 4,374,391 2/15/83 Camlibel et al. 357 17 FOREIGN PATENT DOCUMENTS Translation DOCUMENT DATE COUNTRY **CLASS SUBCLASS** YES NO NUMBER 387175 5/15/65 Switzerland X. OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.) XP-002251628, Anodic bonding technique under low temperature and low voltage using evaporated glass, Woo-Beom Choi et al., 1997 American Vacuum Society, J. Vac. Sci. Technol. B 15(2)

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP §609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

6 March 2006

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